# **Special Issue**

# Accelerometer and Magnetometer: From Fundamentals to Applications

## Message from the Guest Editors

Accelerometers and magnetometers have been widely in consumer electronics, automobiles, precision manufacturing, defense, aerospace and geophysical applications. MEMS technology opens up the possibility to meet the requirements of Cost, Size, Weight and Power (CSWaP), and performance of those applications. Even though, those sensors still suffer scientific barriers towards those applications. Major challenges include but are not limited to: microfabrication processes, new materials, device design and optimization, interface circuits, signal processing and sensors fusions. In addition, new mechanisms which are promising to be implemented by micromachines, such as atomic, optical levitation and optomechanical technologies, are highly interested. This Special Issue calls for the original research papers and reviews with the state-of-the-art results in the relevant topics.

#### **Guest Editors**

Prof. Dr. Huafena Liu

PGMF and School of Physics, Huazhong University of Science and Technology, Wuhan 430074, China

Dr. Yuan Wang

PGMF and School of Physics, Huazhong University of Science and Technology, Wuhan 430074, China

### Deadline for manuscript submissions

closed (31 December 2023)



# **Micromachines**

an Open Access Journal by MDPI

Impact Factor 3.0 CiteScore 6.0 Indexed in PubMed



mdpi.com/si/117873

Micromachines
Editorial Office
MDPI, Grosspeteranlage 5
4052 Basel, Switzerland
Tel: +41 61 683 77 34
micromachines@mdpi.com

mdpi.com/journal/micromachines





an Open Access Journal by MDPI

Impact Factor 3.0 CiteScore 6.0 Indexed in PubMed



## **About the Journal**

## Message from the Editor-in-Chief

You are invited to contribute research articles or comprehensive reviews for consideration and publication in *Micromachines* (ISSN 2072-666X). *Micromachines* is published in the open access format. Research articles, reviews and other contents are released on the internet immediately after acceptance. The scientific community and the general public have unlimited free access to the content as soon as it is published. As an open access journal, *Micromachines* is supported by the authors or their institutes by payment of article processing charges (APC) for accepted papers. We are pleased to welcome you as our authors.

#### Editor-in-Chief

Prof. Dr. Ai-Qun Liu

- 1. Department of Electrical and Electronic Engineering, The Hong Kong Polytechnic University, Hong Kong, China
- 2. School of Electrical and Electronic Engineering, Nanyang Technological University, Singapore 639798, Singapore

#### **Author Benefits**

### **High Visibility:**

indexed within Scopus, SCIE (Web of Science), PubMed, PMC, Ei Compendex, dblp, and other databases.

### Journal Rank:

JCR - Q2 (Instruments and Instrumentation) / CiteScore - Q1 (Mechanical Engineering)

### **Rapid Publication:**

manuscripts are peer-reviewed and a first decision is provided to authors approximately 17.2 days after submission; acceptance to publication is undertaken in 1.9 days (median values for papers published in this journal in the first half of 2025).

